



App No. 09/360,292

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/360,292
Filing Date July 22, 1999
Inventor..... Sujit Sharan et al.
Assignee..... Micron Technology, Inc.
Group Art Unit..... 1765
Examiner Ahmed, Shamim
Attorney's Docket No. MI22-1106
Title: Plasma Etching Process

RESPONSE TO MARCH 15, 2004 OFFICE ACTION

To: Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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AMENDMENTS

Introductory Comments

In response to the Office Action dated March 15, 2004, applicant remarks as follows.